

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appln. No.:

10/736,230

Confirmation No.: 3133

Applicant:

LEVASIER et al.

Filed:

December 16, 2003

Art Unit:

2851

Examiner:

**TBA** 

Docket No.:

081468-0307255

Title:

Lithographic Apparatus with Alignment Subsystem, Device

Manufacturing Method, and Device Manufactured Thereby

## PRELIMINARY AMENDMENT

Commissioner for Patents PO Box 1450 Alexandria, VA 22313-1450

Sir:

Prior to the examination on the merits of the application submitted herewith, the Applicants respectfully request entry of this Preliminary Amendment to the above application as follows: